

IEEE SW Test Workshop

Semiconductor Wafer Test Workshop

Ethan Caughey & Roy Swart
Intel Corporation



Revolutionary new C4 Wafer test probing technologies



June 3-6, 2007
San Diego, CA USA

Outline

- Motivation for looking at new technologies
 - Technical wall
 - Commercial wall
- Process of finding/developing new technologies
 - Next Generation Supplier Investigation Strategy
- Feedback to the C4 wafer test probe card industry
- Successful solutions for next generation C4 wafer test needs
- Key characteristics of the successful wafer test solutions
- Summary

Why we needed to find new alternative technologies

Next generation requirements extend past current capabilities.

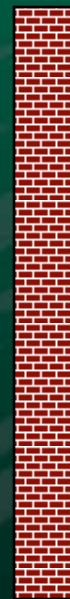
Pitch \rightarrow 175 μ m \longrightarrow X

Cu Bump $\Phi \rightarrow$ 105 μ m \longrightarrow X

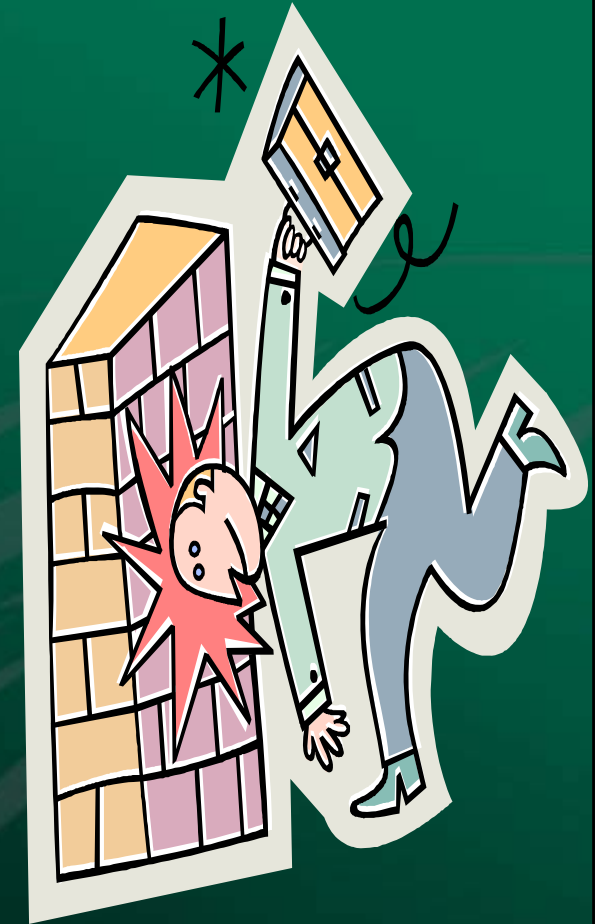
- Tighter scrub control capability
- Tighter alignment and scrub variance control

Parallel Sort \rightarrow 2x \longrightarrow X

- Large array size
- High probe count (beyond 5000)



Technical Wall



Bottom Line: Intel's current probe card suppliers cannot meet next generation technical requirements.

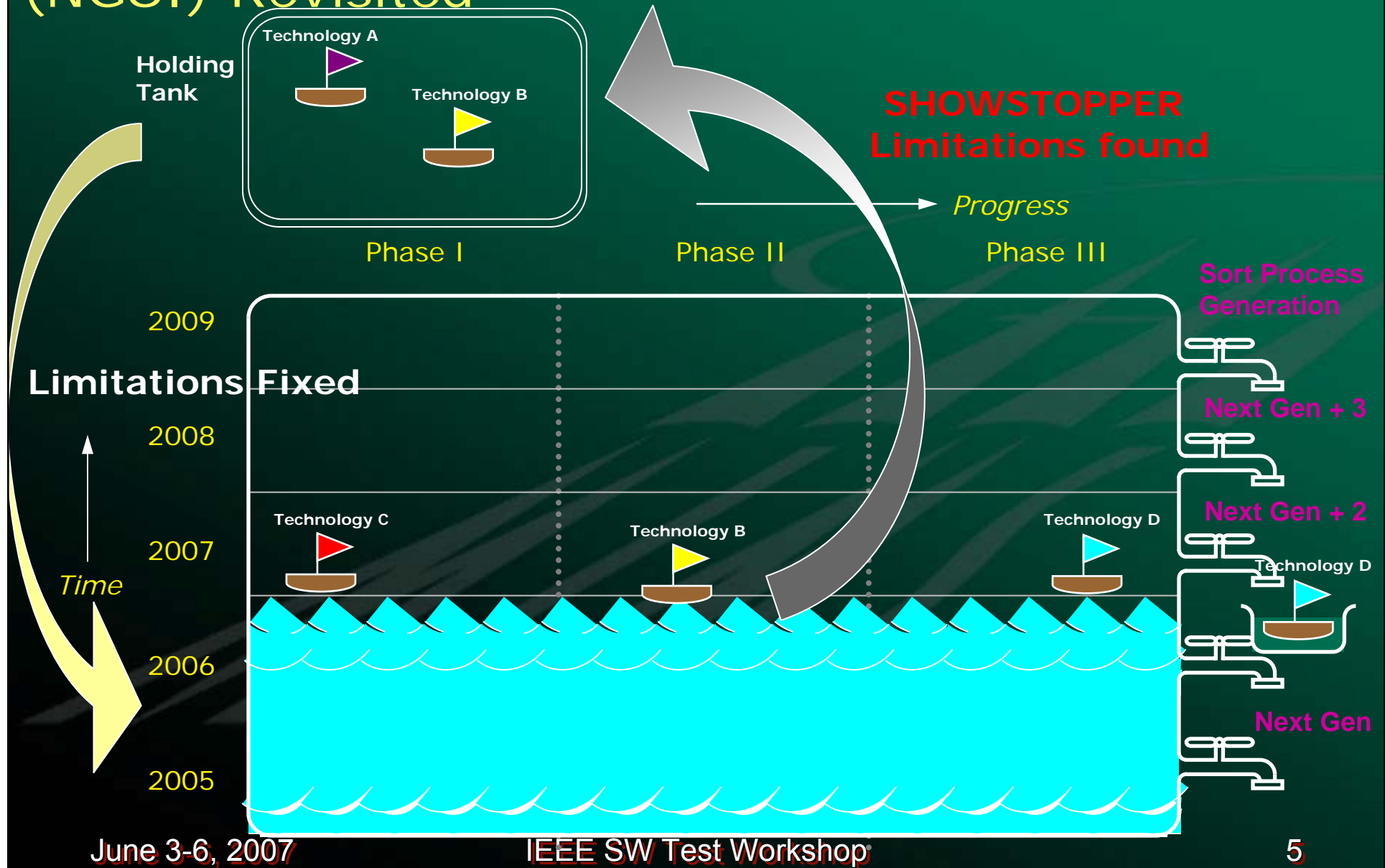
Why we needed to find new alternative technologies

- **Current technologies bound to high cost**
 - Manufacturing process is Labor intensive
 - Manufacturing Process highly complex
 - Cost scales with probe count
 - Limits the ability to extend to parallel sort



Bottom line: Probe card cost is the key limiter to Intel's wafer test process cost reduction capability.

Next Generation Supplier Investigation (NGSI) Revisited

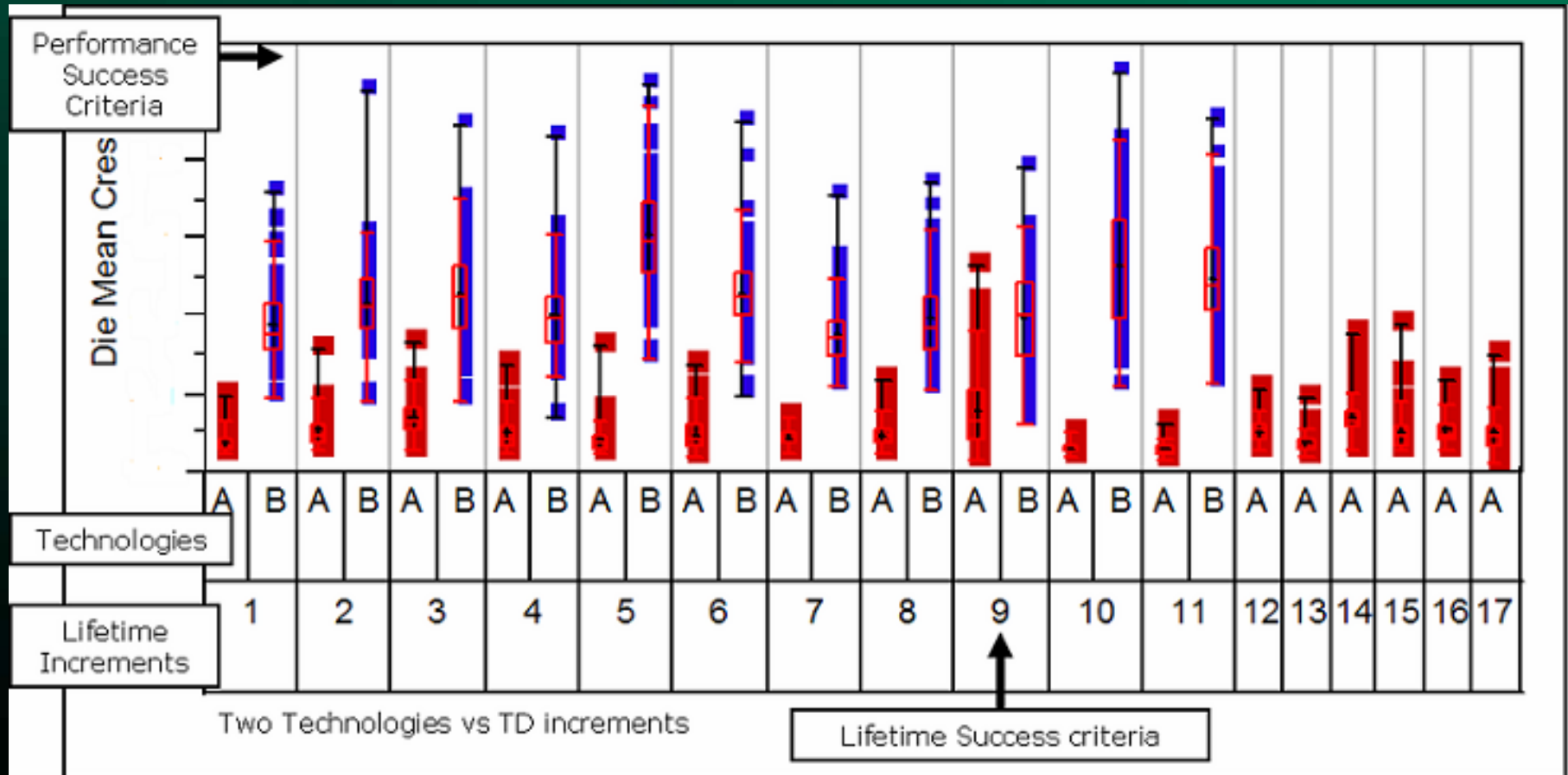


A lot of amazing innovation happening in the probe card industry!!

- **Investigated multiple new unique probing technologies.**
 - Leveraging their core competency and experience.
 - Worked closely with Intel to develop around limitations found
 - **Most solutions have not gone public**
 - Cannot show the great achievements of these companies.
- **Most technologies did not meet our NG requirements.**
 - Many fell out to focus on other business applications.
 - Some still need further development to intercept our process requirements.

Many new probing technologies coming soon!

Two capable new technologies found!!

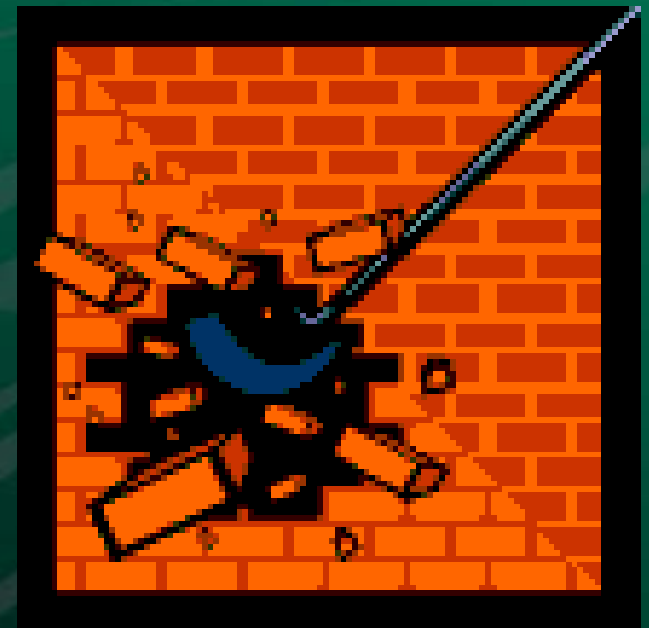


- Lifetime results on two technologies with NG wafer reqs shows proof of concept for these new technologies capable of next generation needs.

Technical Wall Broken

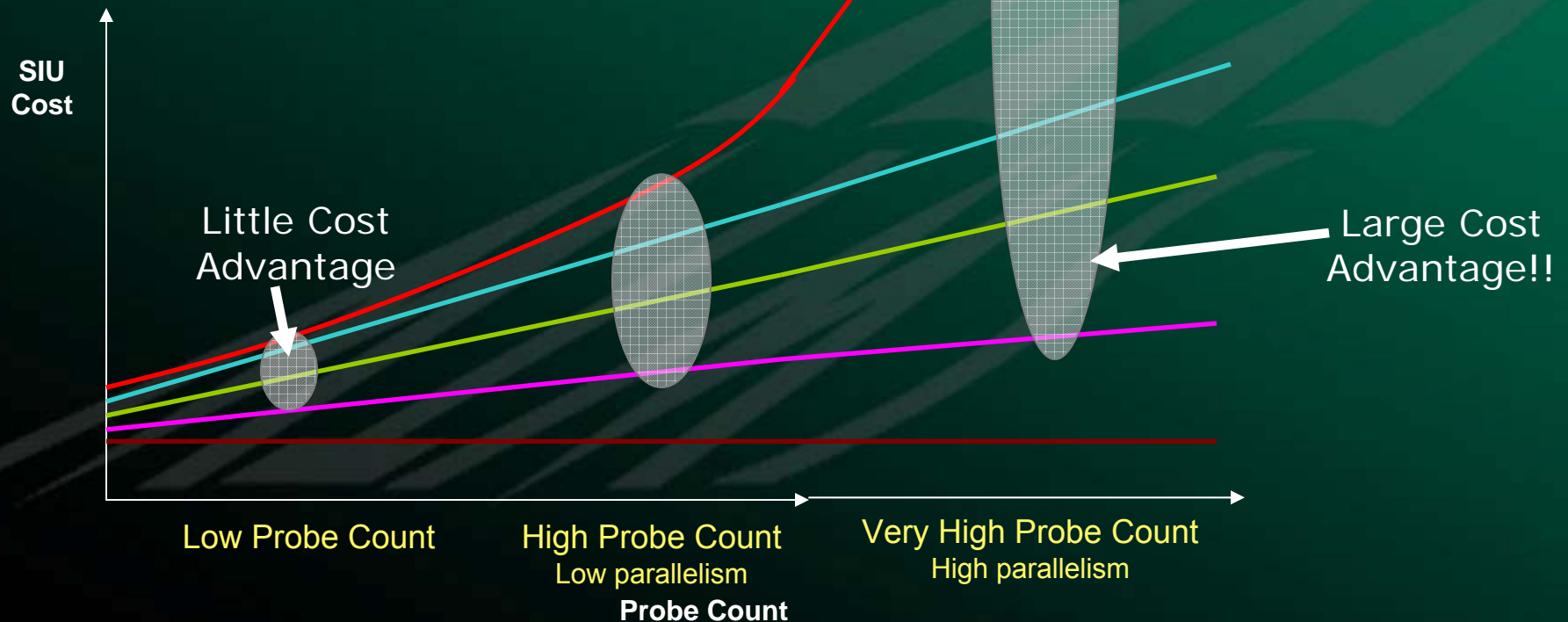
Able to meet critical parameters:

- ✓
 - Reduce pitch (beyond 175um)
 - Reduce bump diameter (beyond 100um)
 - Parallel sort (beyond 2x)
 - Not compromising on other key requirements
 - Current carrying capability
 - Probe Force
 - Inductance
 - Cres Stability
 - Lifetime
- ✓
 - Scalable beyond next generation
 - Not just passed the technical wall but leaps and bounds over the wall for critical requirements.



Commercial wall broken

Decoupling probe count cost dependency!!

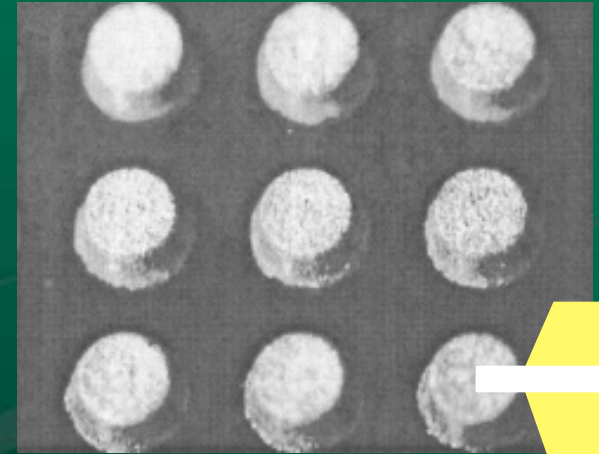


June 3-6, 2007

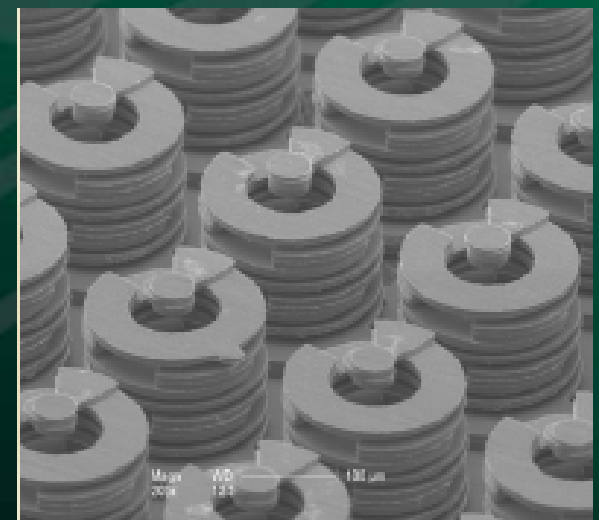
IEEE SW Test Workshop

Probe Characteristics that could break the walls.

- Simple probe geometry
 - Low cost mfg
 - Easy to trouble shoot
- Probe Designed for Simple prober integration
 - Provides simple robust performance
 - Facilitates process development and troubleshooting
- Lithography manufacturing process
 - Batch process mfg reduce probe cost
 - Tight control of probe geometries to control key probe specs



*Figure 1. Elastomer Buttons



*Figure 1. Probes manufactured through EFAB™ Micro-Fabrication process

* See Reference in back for Figure 1 and 2.

Summary

- NGSi methodology used successfully
- Many innovative solutions emerging in C4 wafer test probe card industry
 - Exciting time for C4 wafer test solutions!
- Proof of concept demonstrated to overcome technical and commercial walls.
 - Need to further develop for high volume capability

The Revolution has begun . . .

References

- Swart, R and Caughey, E; “New Pathfinding and Supplier Investigation Strategy”; Intel Corporation; Semiconductor Wafer Test Workshop; June 2007
- Bang, C and Vandelli, N; “Vertical Micro-probe Design Based on the EFAB™ Micro-Fabrication Process”; MEMGen Corporation; Southwest Test Workshop; June 2003
- Xie, J; Hillman, C; Sandborn, P; Pecht, M. G.; Hassanzadeh, A; DeDonato; Assessing the Operating Reliability of Land Grid Array Elastomer Sockets; IEEE Transactions on Components and Packaging Technologies. Vol. 23, NO. 1, March 2000